

2818 #

**COMBINED AMENDMENT & PETITION FOR EXTENSION OF  
TIME UNDER 37 CFR 1.136(a) (Large Entity)**

Docket No. ☒  
OKI.291

In Re Application Of: **Yoshirou Tsurugida**

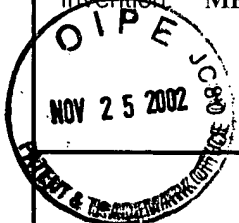
Serial No.  
**10/034,379**

Filing Date  
**01/03/2002**

Examiner  
**NHU, DAVID**

Group Art Unit  
**2818**

Invention: **METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER**



5/1/04  
6-5  
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TO THE ASSISTANT COMMISSIONER FOR PATENTS:

This is a combined amendment and petition under the provisions of 37 CFR 1.136(a) to extend the period for filing a response to the Office Action of 06/25/02 in the above-identified application.  
*Date*

The requested extension is as follows (check time period desired):

☐ One month    ☒ Two months    ☐ Three months    ☐ Four months    ☐ Five months

from: 09/25/02 until: 11/25/02  
*Date* *Date*

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The fee for the amendment and extension of time has been calculated as shown below:

**CLAIMS AS AMENDED**

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	7 -	20 =	0	x \$18.00	\$0.00
INDEP. CLAIMS	1 -	3 =	0	x \$84.00	\$0.00
FEE FOR AMENDMENT					\$0.00
FEE FOR EXTENSION OF TIME					\$400.00
<b>TOTAL FEE FOR AMENDMENT AND EXTENSION OF TIME</b>					<b>\$400.00</b>

11/21/2002 BSAYASII 00000065 09034379

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400.00 DP



Serial No. 10/034,379  
OKI.29T

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of :  
Yoshirou Tsurugida : Group Art Unit 2818  
Serial No. <sup>10</sup>~~09~~7034,379 : Examiner David Nhu  
Filed January 3, 2002 :  
METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

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6. 10/28/02  
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AMENDMENT

Honorable Commissioner For Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated June 25, 2002, the period for response having been extended by a concurrently filed Petition For Extension Of Time, the following amendments and remarks are submitted:

In the Specification<sup>1</sup>

*Kindly rewrite the paragraph bridging pages 4-5 of the specification to read as follows:*

a1 Figs. 1(A) through 1(E) show process steps of a selective oxidation method according to the present invention.

<sup>1</sup> A copy of any revised paragraphs/sections of the specification is attached at ATTACHMENT "A".